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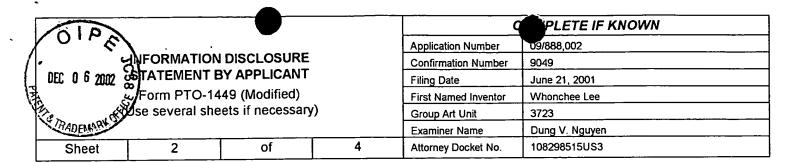
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Form PTO-1449 (Modified) (Use several sheets if necessary)				Confirmation Number	9049	
				Filing Date	June 21, 2001	
	Form PTO-1	449 (Modified)	First Named Inventor	Whonchee Lee		
(Use several sheets if necessary)				Group Art Unit	3723	
OFINALITY				Examiner Name	Dung V. Nguyen	
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